Special Issue

Laser Micro/Nano Fabrication, Second Edition

Message from the Guest Editor

I invite you to contribute to this Special Issue, which seeks research and review articles on laser micro/nanofabrication techniques. These include but are not limited to (1) new laser-based approaches to fabricate micro/nanostructures, (2) subtractive methods, precision laser ablation and cutting, (3) additive methods and laser-induced deposition, (4) laser bonding, welding, and the formation of components; (5) novel software, CAD, and nanometer precision hardware for direct laser writing, and (6) potential research and industrial applications in optical, electronic, and biological fields. Laser micro/nanofabrication is rapidly becoming a preferred manufacturing method due to its inherent high precision, mask-less nature, and rapid processing speed. This Special Issue aims to feature the latest developments in various applications of laser micromachining.

Guest Editor

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You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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